

Supplementary Information for

# Miniature Optical Fiber Accelerometer Based on an In-Situ 3D Microprinted Ferrule-Top Fabry–Pérot Microinterferometer

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*This PDF document includes:*

**Fig. S1** **a** Photo of our own-built in-situ optical 3D microprinting system. **b** Operation schematic diagram and key components of the in-situ optical 3D microprinting system.

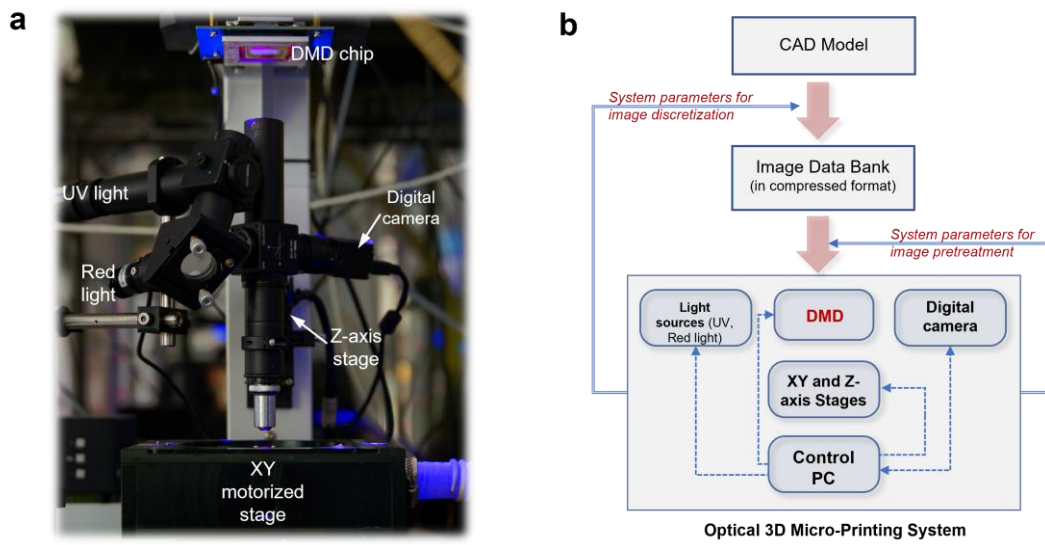
**Fig. S2** **a** Numerical simulation results of the frequency responses of the three designed accelerometers. **b** Simulated displacements of the proof mass and reflection mirror of the three accelerometers with respect to acceleration.

**Fig. S3** Modelling, fabrication, and optical testing results of our third designed accelerometer (i.e., accelerometer 3). **a** (i) CAD model; (ii) Numerical simulation result of the displaced sensor head under 1-g acceleration. **b** Gray-scale pattern for the proof mass, thin-film reflector and supporting microbeams used in optical printing processes. **c** SEM image of a fabricated sensor head. **d** FFT result of the measured reflection spectrum. The inset is the measured reflection spectrums in log scale.

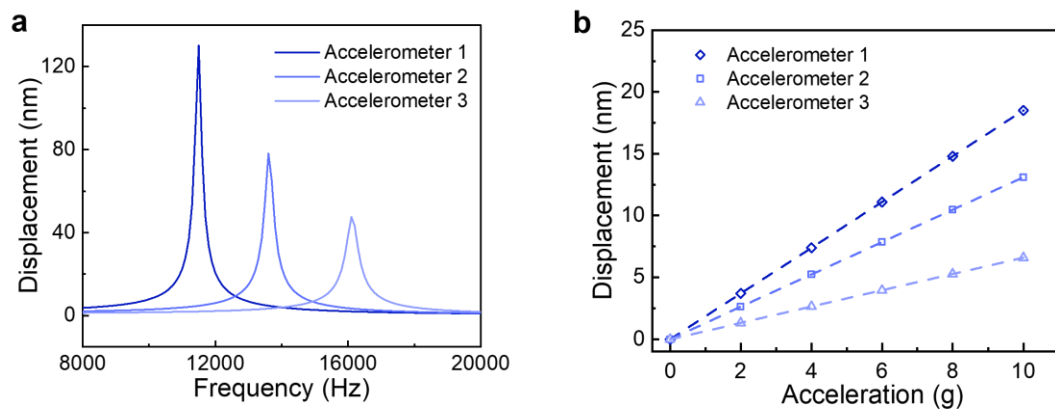
**Fig. S4** **a** Measured dependance of the three accelerometers' outputs on the accelerations at the frequency of 1000 Hz. **b** Measured dependance of the three accelerometers' outputs on the accelerations at the frequency of 2000 Hz.

**Fig. S5** A comparison of the displacements of proof mass and reflection mirror (solid line) deduced from the accelerometers' outputs and their optical sensitivities with numerically simulated displacements (dashed line) under 0-g to 10-g acceleration. **a** Comparison at the frequency of 100 Hz. **b** Comparison at the frequency of 3000 Hz.

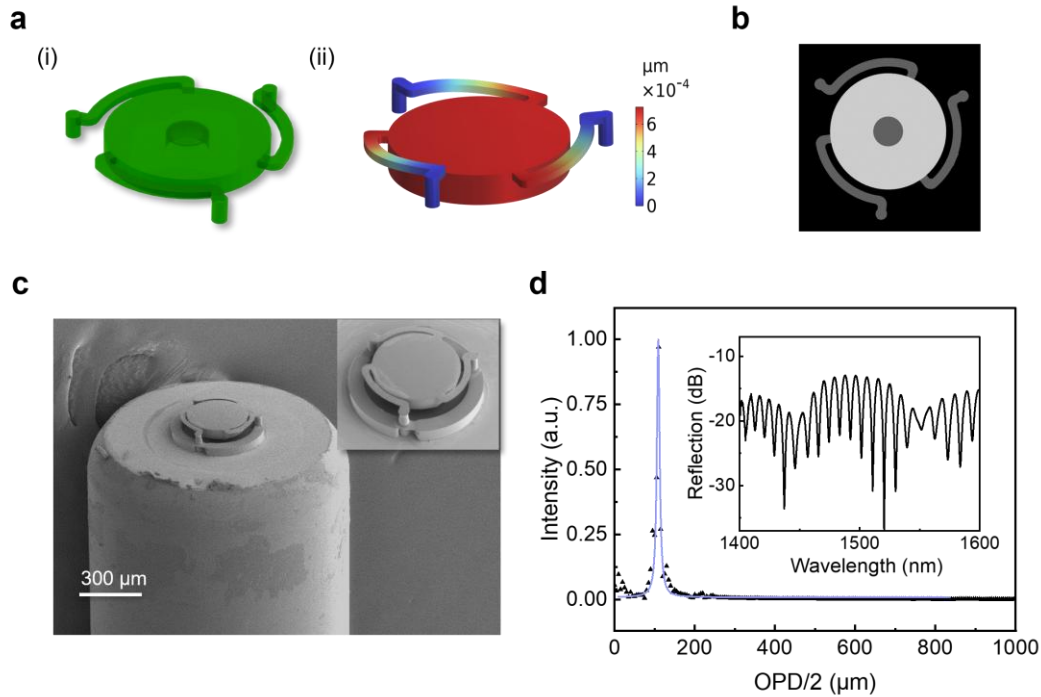
**Table S1** Comparison between the previously reported optical fiber accelerometers and our work.



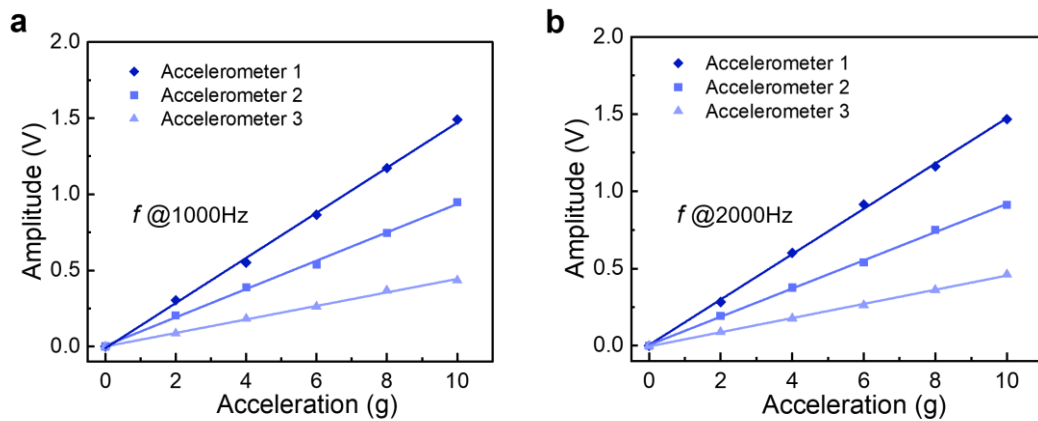
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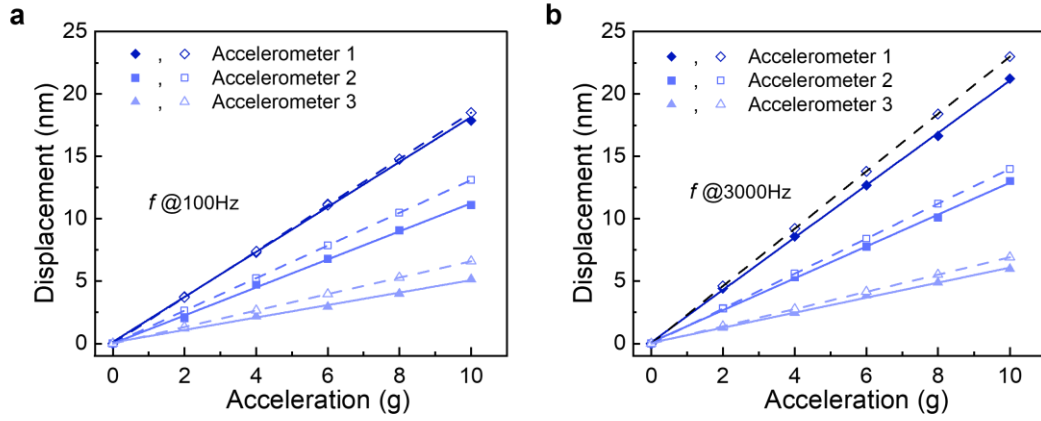
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Publication information	Working mechanism	Dimension of sensor head (mm)	Bandwidth	Resolution ( $\mu\text{g}$ ) /NEA ( $\mu\text{g}\cdot\text{Hz}^{-1/2}$ )	Sensitivity
Li <i>et al.</i> , <i>IEEE Sen. J.</i> <b>22</b> , 23931 (2022)	FBG-FP	13×10×5	600 Hz	1500 $\mu\text{g}$	27.3 $\text{mV}\cdot\text{g}^{-1}$
Zhao <i>et al.</i> , <i>J. Light. Tech.</i> <b>36</b> , 1562 (2017)	FPI	$\Phi 2.5\times 5$	120 Hz	8.5 $\mu\text{g}$	3.86 $\mu\text{m}\cdot\text{g}^{-1}$
Wang <i>et al.</i> , <i>Opt. Fib. Tech.</i> <b>72</b> , 102989 (2022)	FPI	$\Phi 25\times 10$	300 Hz	263 $\mu\text{g}$	3.81 $\text{nm}\cdot\text{g}^{-1}$
Zhang <i>et al.</i> , <i>Opt. Engi.</i> <b>57</b> , 087107 (2018)	FPI	$\Phi 1\times 2.5$	1500 Hz	350 $\mu\text{g}\cdot\text{Hz}^{-1/2}$	2.9 $\text{nm}\cdot\text{g}^{-1}$
Bruno <i>et al.</i> , <i>J. Light. Tech.</i> <b>38</b> , 1998 (2020)	FPI	2×3×3	4800 Hz	101.25 $\mu\text{g}\cdot\text{Hz}^{-1/2}$	0.98 $\text{nm}\cdot\text{g}^{-1}$
This work	FPI	$\Phi 0.4\times 0.1$	2000 Hz	62.45 $\mu\text{g}\cdot\text{Hz}^{-1/2}$	1.8 $\text{nm}\cdot\text{g}^{-1}$